



# Facilities & Gases North America Joint TC Chapter

SEMICON West 2017 Standards Meetings

Tuesday, July 11, 2017,

Marriott Marquis Hotel, San Francisco, CA

09:00–12:00 Noon

## AGENDA

	<b>Presenter</b>
<b>1 Welcome/Call to Order</b>	<b>Co-chairs</b>
1.1 Introductions	
1.2 Required Elements (Membership Requirements, Antitrust and Intellectual Property Reminders, and Effective Meeting Guidelines)	
1.3 Agenda Review	
<b>2 Review of Previous Meeting Minutes</b>	<b>Co-chairs</b>
<b>3 Liaison Report</b>	<b>Staff</b>
3.1 Europe TC Chapter	
3.2 Japan TC Chapter	
<b>4 Staff Report</b>	<b>Staff</b>
<b>5 Ballot Review</b>	<b>Leaders</b>
<i>Facilities</i>	
5.1 Document 5155A — New Standard, Guide for Facilities Data Package for Semiconductor Equipment Installation and Building Information Modeling	
<i>Gases</i>	
5.2 Document 6178 — Line Item Revision to Correct the Title of SEMI F37-0299 (Reapproved 0611), Method for Determination of Surface Roughness Parameters for Gas Distribution System Components	
5.3 Document 6056B — Revision to SEMI E28-1110, Guide for Pressure Specifications of the Mass Flow Controller	
5.4 Document 6180 — Reapproval of SEMI F64-0701 (Reapproved 1111), Test Method for Determining Pressure Effects on Indicated and Actual Flow for Mass Flow Controllers	
5.5 Document 6181 — Reapproval of SEMI F76-0303 (Reapproved 1110), Test Method for Evaluation of Particle Contribution from Gas System Components Exposed to Corrosive Gas	



**Presenter**

- 5.6 Document 6188 — Reapproval of SEMI F54-1000 (Reapproved 1110), Test Method for Measuring the Counting Efficiency of Condensation Nucleus Counters
- 5.7 Document 6182 — Reapproval of SEMI C9.1-0212, Guide for Analysis of Uncertainties in Gravimetrically Prepared Gas Mixtures
- 5.8 Document 6186 — Reapproval of SEMI C3.58-1011, Specification for Octafluorocyclobutane, C4F8, Electronic Grade in Cylinders, 99.999% Quality

**6 Subcommittee & Task Force Reports**

**Leaders**

*Gases*

- 6.1 Materials of Construction of Gas Delivery Systems
- 6.2 Filters and Purifiers
- 6.3 Mass Flow Controller
- 6.4 Gases Specification
- 6.5 Heater Jacket

*Facilities*

- 6.6 SEMI F51 Revision
- 6.7 Building Information Modeling (BIM) for Semiconductor Capital Equipment
- 6.8 Power Grid Harmonics

**7 Old Business**

**Co-chairs**

- 7.1 Standards due for Five-Year Reapproval
- 7.2 SNARFs approaching Three-Year Document Developing Period

**8 New Business**

**Co-chairs**

- 8.1 New TFOF (s) and SNARF(s); if any
- 8.2 Upcoming Ballot(s)

**9 Action Item Review**

**Staff**

- 9.1 Open Action Items
- 9.2 New Action Items



**Presenter**

## **10 Next Meeting and Adjournment**

**Co-chairs**

10.1 The next meeting is scheduled for November 7 at SEMI Headquarters in Milpitas, California.

### Tentative Schedule:

Monday, November 6

#### Gases Task Force Meetings

09:00-10:00 Materials of Construction of Gas Delivery Systems (TF)

10:00-11:00 Filters and Purifiers (TF)

11:00-12:00 Mass Flow Controller (TF)

13:00-14:00 Gas Specification (TF)

14:00-15:00 Heater Jacket (TF)

#### Facilities Task Force Meetings

13:00-14:00 Power Grid Harmonics (TF)

15:00-16:00 SEMI F51 (Perfluoroelastomer) (TF)

15:00-17:00 Building Information Modeling (BIM) for Semiconductor Capital Equipment (TF)

Tuesday, November 7

09:00-12:00 Facilities & Gases (C)

2017/06/02

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